

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re new PATENT application of)
Koichiro TANAKA et al.)
Based on JP 2003-054695) New Applications
Filed: February 28, 2003)
For: LASER IRRADIATION METHOD, LASER)
IRRADIATION APPARATUS, AND)
METHOD FOR MANUFACTURING)
SEMICONDUCTOR DEVICE)

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Before examination of the above-identified application, please amend the title as follows:

Amendments to the Title begin on page 2 of this paper.

Remarks begin on page 3 of this paper.

Amendments to the Title:

Please amend the Title of the Invention beginning on Page 1 of the Specification as follows:

**LASER IRRADIATION METHOD, LASER IRRADIATION APPRATUS APPARATUS,
AND METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE**